

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 62-101408

(43)Date of publication of application : 11.05.1987

(51)Int.Cl.

B29C 35/02
C08F 2/48

(21)Application number : 60-243073

(71)Applicant : OSAKA PREF GOV

(22)Date of filing : 29.10.1985

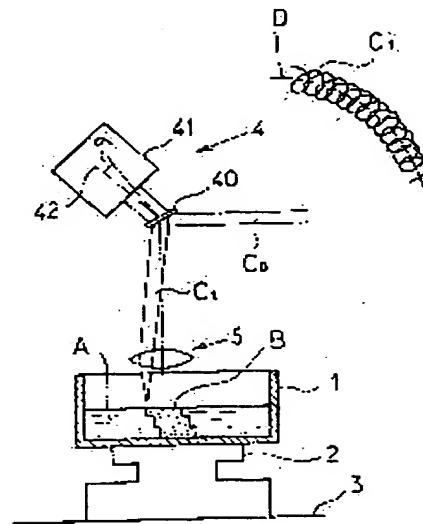
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(54) OPTICAL SHAPING

(57)Abstract:

PURPOSE: To shape the solid of a desired thickness with a high dimensional accuracy by a method wherein projecting light flux is moved along a main path as a whole while effecting repeated micro-motions covering the main path along the sectional configuration of a solid to be shaped and the periphery of the main path to shape the sectional configuration.

CONSTITUTION: When laser beams are projected against a plane mirror 40 while rotating the plane mirror 40 about an axial line 42 by a driving unit 41, reflecting light oscillates along a conical surface having the central angle of 2α and the beams are collected on a photo-setting substance A through a lens device 5. According to this method, light projection, accompanied by repeated micro-motions, can be effected. A vessel 1 is moved relatively with respect to the laser beams C1 by a position control unit 2 while effecting the repeated micro-motions and the laser beams C1 are moved relatively along the main path along the configuration of the solid to be shaped, then, a desired sectional configuration may be obtained. Thereafter, adding of the photo-setting substance of a predetermined depth and the selective light projection same as above-described manner are repeated while accompanying the descending of the vessel 1, whereby the solid B of a desired configuration may be obtained with a high dimensional accuracy.



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[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's

decision of rejection]

[Date of extinction of right]

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